

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Hideaki SAKURAI, et al.

SERIAL NO: New Application

GAU:

FILED: Herewith

EXAMINER:

FOR: PROTECTIVE FILM FOR FPD, VAPOR DEPOSITED MATERIAL FOR PROTECTIVE FILM AND ITS PRODUCTION METHOD, FPD, AND MANUFACTURING DEVICE FOR FPD PROTECTIVE FILM

INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

SIR:

Applicant(s) wish to disclose the following information.

REFERENCES

- ☒ The applicant(s) wish to make of record the references listed on the attached form PTO-1449. Copies of the listed references are attached, where required, and were cited and/or made of record in the parent application U.S. serial no. 09/901,908, filed on July 11, 2001.
- ☐ A check is attached in the amount required under 37 CFR §1.17(p).

RELATED CASES

- ☐ Attached is a list of applicant's pending application(s) or issued patent(s) which may be related to the present application. A copy of the patent(s), together with a copy of the claims and drawings of the pending application(s) is attached along with PTO 1449.
- ☐ A check is attached in the amount required under 37 CFR §1.17(p).

CERTIFICATION

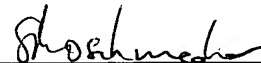
- ☐ Each item of information contained in this information disclosure statement was first cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.
- ☐ No item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application or, to the knowledge of the undersigned, having made reasonable inquiry, was known to any individual designated in 37 CFR §1.56(c) more than three months prior to the filing of this statement.

DEPOSIT ACCOUNT

- ☒ Please charge any additional fees for the papers being filed herewith and for which no check or credit card payment form is enclosed herewith, or credit any overpayment to deposit account number 15-0030. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,
MAIER & NEUSTADT, P.C.



Norman F. Oblon

Registration No. 24,618



22850

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 241584US0CONT		SERIAL NO. New Application	
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT Hideaki SAKURAI, et al.			
				FILING DATE Herewith		GROUP	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA	5,891,531	01-1999	KONISHI, ET AL.			
	AB	5,496,583	03-1996	JANSEN, ET AL.			
	AC	5,462,922	10-1995	DOI, ET AL.			

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION	
					YES	NO
	AD	2001-035382A	02-2001	JAPAN		
	AE	2000-331601A	11-2000	JAPAN		
	AF	41049767A	06-1998	JAPAN		
	AG	96/19825	06-1996	WIPO (corresponding to JP 10-512100)		
	AH	10-512100	11-1998	JAPAN (w/English Abstract)		
	AI	10-149767	06-1998	JAPAN (w/English Abstract)		
	AJ	2741546	01-1998	JAPAN (w/English Abstract)		
	AK	87-01508	03-1987	WIPO (corresponding to JP 6-26206)		
	AL	6-26206	04-1994	JAPAN (w/English Abstract)		
	AM	10-101830	04-1998	JAPAN (w/English Abstract)		
	AN	10-204195	08-1998	JAPAN (w/English Abstract)		
	AO	09-040881	02-1997	JAPAN (w/English Abstract)		
	AP	10-182861	07-1998	JAPAN (w/English Abstract)		

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)

	AQ	Vossen, John L., "Thin Film Process", Academic Press, 1978, Pages 438-439.	
	AR	H., Seehase, "Plasma Display Panel MgO Thin Film Properties and Their Modification by Low Energy Ion Bombardment", Displays, January 1985, Pages 21-34.	
	AS	Monthly Semiconductor World, [3], 1998, Pages 121-123.	
	AT	Excalibur Paper Phase Cleaning System Described in the Catalog of MFSI Co., Ltd.	
	AU	FALCON HF Reduced Pressure Gas Phase Etching System Described in the Catalog of ASM Japan Co., Ltd.	
	AV	M.N. Abraham, et al., "Growth of High Purity and Doped Alkaline Earth Oxides: I. MGO and CaO", The Journal of Chemical Physics, 35[8], 1971, Pages 3752-3756.	
	AW	"The Latest Plasma Display Manufacturing Technology", Press Journal, Inc. December 1, 1997.	
	AX	Lee, W.T., "Study of Protective Layers in AC-PDPs", IDW 99, Pages 763-766.	
	AY	"Preparation of MgO Protective Films for Plasma Display Panels Using Vacuum Deposition Methods", ULVAC Technical Journal, No. 46, 1997, Pages 8-13.	
	AZ	"Cathode Materials for Color Plasma Displays", O Plus E, February 1996.	<input type="checkbox"/> Additional References sheet(s) attached
Examiner		Date Considered	
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.			